

U.S. Patent Application Serial No. **10/516,949**
Amendment filed April 13, 2010
Reply to OA dated June 3, 2009

AMENDMENTS TO THE CLAIMS:

Please amend claims 1 and 9, and cancel claims 5 and 13, as follows. This listing of claims will replace all prior versions, and listings, of claims in the application:

Listing of Claims:

Claim 1 (Previously Presented): A substrate treatment apparatus, comprising:

a substrate holding unit holding a substrate to be treated;

a substrate spinning unit spinning the substrate to be treated held on said substrate holding unit;

a treatment solution supply unit supplying a plurality of treatment solutions onto the substrate to be treated; and

a treatment solution collection unit having a plurality of collection tanks placed in a manner to surround a periphery of the substrate to be treated held on said substrate holding unit, and provided to separately collect by kind the treatment solutions scattered by said substrate spinning unit from the substrate to be treated,

wherein said treatment solution collection unit collects the treatment solution by one of the collection tanks with inlets of the other collection tanks closed, and

wherein said treatment solution collection unit has a plurality of fences which sets each collection tank in said plurality of correction tanks, and when said plurality of treatment solutions

U.S. Patent Application Serial No. 10/516,949
Amendment filed April 13, 2010
Reply to OA dated June 3, 2009

is collected, said plurality of fences is respectively driven only upwards to separately collect said plurality of treatment solutions by kind with each corresponding collection tank,

wherein the fence has a tip portion formed to be a reflective face that is curved to reflect the treatment solution scattered from the substrate to be treated to lead the treatment solution into the collection tank selected.

Claim 2 (Canceled).

Claim 3 (Previously presented): The substrate treatment apparatus according to claim 1, wherein a position of the substrate to be treated held on said substrate holding unit is located above positions of the fences which are not collecting any treatment solution of said plurality of treatment solutions.

Claim 4 (Previously presented): The substrate treatment apparatus according to claim 1, wherein:

the plurality of fences are arranged overlapping one another in order, from the fence closer to the substrate to be treated, in a manner to close the inlets of the plurality of collection tanks; and

said treatment solution collection unit performs collection in order, starting from the collection tank at a position farther from the substrate to be treated.

U.S. Patent Application Serial No. **10/516,949**
Amendment filed April 13, 2010
Reply to OA dated June 3, 2009

Claim 5 (Canceled):

Claim 6 (Original): The substrate treatment apparatus according to claim 1, wherein exhaust units separately exhausting internal gasses are provided for the collection tanks, respectively.

Claim 7 (Original): The substrate treatment apparatus according to claim 1, wherein drain units draining the treatment solutions are provided for the collection tanks, respectively.

Claim 8 (Original): The substrate treatment apparatus according to claim 1, further comprising a cleaning unit cleaning the inside of said collection tanks.

Claim 9 (Previously Presented): A substrate treatment method, comprising the steps of:
supplying a plurality of treatment solutions onto a held substrate to be treated while spinning the substrate; and

when using a treatment solution collection unit having a plurality of collection tanks placed in a manner to surround a periphery of the substrate to be treated and provided to separately collect by kind the treatment solutions scattered from the substrate to be treated, to collect the treatment solution by one of the collection tanks, collecting the treatment solution only by the one of the collection tanks with inlets of the other tanks closed, and

wherein said treatment solution collection unit has a plurality of fences which sets each collection tank in said plurality of correction tanks, and when said plurality of treatment solutions is collected, said plurality of fences is respectively driven only upwards to separately collect said plurality of treatment solutions by kind with each corresponding collection tank,

wherein the fence has a tip portion formed to be a reflective face that is curved to reflect the treatment solution scattered from the substrate to be treated to lead the treatment solution into the collection tank selected.

Claim 10 (Canceled).

Claim 11 (Previously presented): The substrate treatment method according claim 9, wherein a position of the held substrate to be treated is located above positions of the fences which are not collecting any treatment solution of said plurality of treatment solutions.

Claim 12 (Previously presented): The substrate treatment method according claim 9, wherein:
the plurality of fences are arranged overlapping one another in order, from the fence closer to the substrate to be treated, in a manner to close the inlets of the plurality of collection tanks; and
said step of collecting the treatment solution performs collection in order, starting from the collection tank at a position farther from the substrate to be treated.

U.S. Patent Application Serial No. **10/516,949**
Amendment filed April 13, 2010
Reply to OA dated June 3, 2009

Claim 13 (Canceled):

Claim 14 (Original): The substrate treatment method according claim 9, further comprising an exhausting step of separately exhausting internal gasses for the collection tanks, respectively.

Claim 15 (Original): The substrate treatment method according claim 9, further comprising a drain step of draining the treatment solutions for the collection tanks, respectively.

Claim 16 (Original): The substrate treatment method according claim 9, further comprising a cleaning step of cleaning the inside of the collection tanks.